

## **Keywords for Microsystems Fabrication using Advanced Machining Processes**

- (1) MEMS
- (2) Microsystems
- (3) Microsystems Applications
- (4) Microfluidics
- (5) Silicon MEMS
- (6) Polymer MEMS
- (7) Softlithography
- (8) Deep Reactive Ion Etching
- (9) Photolithography
- (10) LIGA
- (11) Compression Molding
- (12) Dip pen lithography
- (13) Hot embossing
- (14) Micro Contact Printing
- (15) Czochralsky growth method
- (16) Etch selectivity
- (17) Poly Dimethyl Siloxane (PDMS)
- (18) Poly methyl methacrylate (PMMA)
- (19) Float Zone Method
- (20) Plasma
- (21) DC glow discharge
- (22) RF plasma
- (23) Magnetically Enhanced Plasma
- (24) Photoresists
- (25) SU8
- (26) S1813
- (27) Thermal oxidation.
- (28) Bulk and surface micromachining
- (29) Doping and Ion implantation
- (30) Thermal Evaporation
- (31) Deposition techniques
- (32) Sputtering
- (33) E-Beam Evaporation
- (34) Lift Off techniques
- (35) Anisotropic and isotropic wet etching techniques
- (36) Micro-stereo-lithography
- (37) Abrasive Jet machining
- (38) Electrochemical Machining
- (39) Electrochemical Micromachining
- (40) Electric Discharge Machining
- (41) Laser Machining
- (42) Electron beam machining

- (43) Nano imprint lithography
- (44) E-Beam Lithography
- (45) Plasma Arc Machining
- (46) Ion Beam Machining
- (47) Focussed Ion Beam
- (48) Rapid Prototyping
- (49) 3-D printing
- (50) Electrostatic Dual layer